



Attorney Docket No. 0756-7259

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Koichiro TANAKA et al.

Serial No. 10/787,120

Filed: February 27, 2004

For: LASER IRRADIATION METHOD,  
LASER IRRADIATION APPARATUS,  
AND METHOD FOR  
MANUFACTURING  
SEMICONDUCTOR DEVICE

) Group Art Unit: 2818

) Examiner: Chuong A. Luu

) CERTIFICATE OF MAILING

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) 2007

) 

**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated March 22, 2007, please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 10 of this paper.